

Maurizio Vannoni X-ray Optics Group European XFEL, Schenefeld (Hamburg area), Germany

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#### **Photon Beamlines**

Undulator Segment	FEL radiation energy [keV]	Wavelength [nm]
SASE 1	3 - over 24	0.4 - 0.05
SASE 2	3 - over 24	0.4 - 0.05
SASE 3	0.27 - 3	4.7 – 0.4



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Low level of vibrations

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# What are the challenges/opportunities for optics and mechanics?

Size of the beam: from 1 mm to 3 mm

Low drift, mechanical stability
Low drift, mechanical stability
1 Km
1 microradian mirror rotation

= 500 nm of translation each side on the mirror

• Preservation of optical properties on the nm level



## Level of polishing required ("magic number" depending only on material)

(Sinn, Samoylova, et al., "X-ray Optics and Beam Transport CDR", April 2011 and F. Siewert et al., Optics Express 20, 4525)



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Simulations in practical case of EXFEL SASE1 M1

Euro (Thanks to Liubov Samoylova , European XFEL)

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Grazing incidence setup (faster but less accurate)





Stitching normal incidence setup (more accurate but longer time)



14

Measurements before and after coating, extremely reproducible (not mounted)



(shape is induced with deterministic polishing to correct gravitational deformation)

At this level the calibration of the Fizeau (reference alignment) and the alignment of the test mirror is not good enough...so the coating could be even better

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#### **Vibrations**



Design by Tino Noll and Antje Trapp Produced by CINEL (Italy)



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t T VI 1.2250 0.9800 0.7350 Measurement Value 250 nm < P-V < 300 nm 0.4900 0.2450 0.0000 Peak Amplitude 80.700 nm -0.2450 mon -0.4900 Peak Freque... -0.7350 12.274 Hz -0.9800 -1.2250 d 0.2 0.4 0.6 0.8 1.0 1.2 1.4 1.6 1.8 2.0 2.2 2.4 Peak Amplitude 2.769 nm (µm) 2 -120.4 Peak Freque... 47.209 Hz -138.8 -157.2 Peak Amplitude 1.136 nm -175.6 and which a show a property of the second of -194.0 Peak Freque... 19.828 Hz -212.4 -230.8 -249.2 -267.5 -285.9 -304.3 50 100 150 200 250 300 350 450 500 400 dB [0dB = 1m] Frequency (Hz) Channel Measurement Value Min Max Average Capture Count Taken From Peak Amplitude 80.700 nm 80,700 nm 80,700 nm 80,700 nm 1 Spectrum A... Visible Trace 12.274 Hz 12.274 Hz 12.274 Hz 2 Spectrum Fr... Peak Freque... 12.274 Hz Visible Trace 3 Spectrum A... Peak Amplitude 2.769 nm 2.769 nm 2.769 nm 2.769 nm 1 Visible Trace 47.209 Hz 47.209 Hz 47.209 Hz 4 Spectrum Fr... Peak Freque... 47.209 Hz 1 Visible Trace 1.136 nm 5 Spectrum A... Peak Amplitude 1.136 nm 1.136 nm 1.136 nm Visible Trace 1 19 928 Hz 6 Spectrum Fr... Peak Freque... 19.828 Hz 19.828 Hz 19.828 Hz 1 Visible Trace

#### Installation: stiction forces on mirror supports

Residual stress after mounting or due to thermal expansion



#### + side fiducials or other parts in contact

(Thanks to Harald Sinn, X-ray Optics Group Leader, European XFEL)



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#### Stiction force effect in simulations



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#### Stiction force effect in action !



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Mounting a mirror can introduce stresses and deformations. That's why the optics have to be measured in their final mount

Here an example of reproducibility of installations in a fixed mount.

(Thanks to Silja Schmidtchen, European XFEL)

21

#### Conclusions

We presented here the general activity of metrology carried out at European XFEL :

Grazing incidence (when we have to rush) and stitching method (when we have time)

General reproducibility and repeatability very good

Results compatible with expectations from measurements

What is still missing ?

Study of the repeatability of the installation and development of a strategy to ensure a better installation (keeping the good measurements done in the lab)

Automatization of the procedure

- Extension of the procedure to very curved mirrors (only stitching possible but the number of subapertures is increasing)
- Diagnostics on site (after installation)

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